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PATENT
11-14-00
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 08/682,935

Filed: July 16, 1996

For: TECHNIQUE FOR ELIMINATION
OF PITTING ON SILICON SUBSTRATE
DURING GATE STACK ETCH

Examiner: H. Nguyen

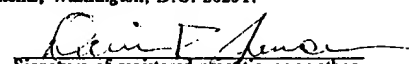
Group Art Unit: 2812

Attorney Docket No.: 2915.2US
(96-0149)

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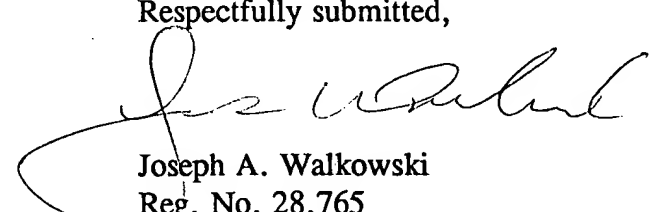
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Sir:

In accordance with 37 C.F.R. § 1.34(b), please recognize the following individual as an associate agent/attorney herein in connection with the above-identified patent application:

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